

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.	Serial No.			
				M-15319 US	<u>Unassigned</u>			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				Applicant(s)	10/758987			
				Yin S. Tang				
				Filing Date 1/26/04	Group 2873			
				<u>None with</u>	<u>Unassigned</u>			
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DVS	AA	4,541,727	09/17/1985	Rosenthal	368	232		
DVS	AB	6,129,866	10/10/2000	Hamanaka et al.	264	1.7		
DKS	AC	6,335,828	01/01/2002	Hashimoto et al.	359	443		
DVS	AD	6,582,988	06/24/2003	Hsiao et al.	438	70		
DVS	AE	6,654,174	11/25/2003	Huang	359	619		
	AF							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AG							
	AH							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
DKS	AI	B. Volckaerts et al., <u>The Fabrication of Cylindrical Micro-Lens Arrays with Deep Lithography with Protons</u> , Cyclotron Department VUB, Laarbeeklaan 103, 1090 Brussels, Belgium						
	AJ							
DS								
Examiner		Date Considered 6/10/2005						
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>								

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